

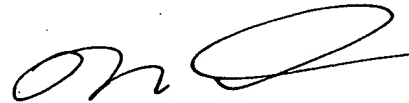
REMARKS

The accompanying CPA Request Transmittal and this paper are submitted in reply to the final Office Action of August 23, 2002 (Paper No. 18). Claims 1-5 are cancelled hereby. New claims 6-11 are substituted for the prior claims.

Action on the merits with respect to the new claims is solicited.

Respectfully submitted,

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NEW CLAIMS 6-11

6. A laser intensity adjusting method of adjusting a maximum intensity of a laser exposure mechanism for irradiating laser light to a surface of a photoreceptor to which a uniform potential is being given by a corona discharger, said method comprising:

a first potential detecting step including the steps of (i) obtaining a first plurality of laser intensity values that increase from an initial value to a predetermined value according to a first interval to provide a first range of intensity values, (ii) successively exposing a surface portion of the photoreceptor surface with laser light having intensities corresponding to said first plurality of intensity values to provide a plurality of exposed patch portions on the photoreceptor surface, and (iii) detecting the potential of each of said plurality of exposed patch portions;

a second potential detecting step including the steps of (i) obtaining a second plurality of laser intensity values that increase from an initial value to a predetermined value according to a second interval to provide a second range of intensity values, said second interval being smaller than said first interval and said second range being smaller than said first range, (ii) successively exposing a surface portion of said photoreceptor surface with laser light having intensities corresponding to said second plurality of intensity values to provide a plurality of patch portions on the photoreceptor surface; and (iii) detecting the potential of each of said plurality of exposed patch portions; and

a step of setting, as a maximum intensity of the laser exposure mechanism, a laser intensity with which there has been detected, at said first or said second potential detecting step, a potential equal to or substantially equal to a predetermined set potential,

wherein said laser intensities corresponding to said second plurality of intensity values are selected to be close to a laser intensity value corresponding to a potential detected during said first potential detecting step as closest to said predetermined set potential.

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7. A laser intensity adjusting method according to claim 6, wherein said second potential detecting step is repeated until there is obtained a potential equal to or substantially equal to said predetermined set potential.

8. A laser intensity adjusting method according to claim 6, wherein said laser intensity values obtained at first potential detecting step have values selected from a plurality of laser intensities obtained by dividing said predetermined laser intensity value of said first potential detecting step by a first predetermined number.

9. A laser intensity adjusting method according to claim 6, wherein said laser intensity values obtained at said second potential detecting step have values selected from a plurality of laser intensities obtained by dividing said

predetermined laser intensity value of said second potential detecting step by a second predetermined number.

10. A laser intensity adjusting method according to claim 8, wherein
said predetermined laser intensity value is set to a value which is greater
than a suitable maximum intensity.

11. A laser intensity adjusting method according to claim 9, wherein
said predetermined laser intensity value is set to a value which is greater
than a suitable maximum intensity.

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